



PTO/SB/08A (08-03)

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Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT***(use as many sheets as necessary)*

Sheet 1 of 4

Complete if Known

Application Number	10/666,527
Filing Date	18 Sept 2003
First Named Inventor	Bailey et al
Group Art Unit	1722
Examiner Name	Emmanuel S. Luk
Attorney Docket Number	PA51-22-02

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			

EL	E1	2003/0180631	A1	Shiota et al.	9/25/2003	
	E2	6,664,026	B2	Nguyen et al.	12/16/2003	
	E3	6,261,469	B1	Zakhidov et al.	7/17/2001	
	E4	5,817,376		Everaerts et al.	10/6/1998	
	E5	6,986,975	B2	Sreenivasan et al.	1/17/2006	
	E6	2006/0019183	A1	Voisin	1/26/2006	
	E7	3,677,178		Gipe	7/18/1972	
	E8	6,743,368	B2	Lee	6/1/2004	
	E9	2005/0236360	A1	Watts et al.	10/27/2005	
	E10	6,399,406	B2	Chan et al.	6/4/2002	
	E11	6,605,849	B1	Lutwak et al.	8/12/2003	
	E12	6,607,173	B2	Westmoreland	8/19/2003	
	E13	7,037,639	B2	Voisin	5/2/2006	
EL	E14	2006/0096949	A1	Watts et al.	5/11/2006	

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				Attorney Docket Number	PA51-22-02
Sheet	2	of	4		

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cita No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

EL	E15	Translation of Japanese Patent 61-40845, 2/1/1986	
EL	E16	Translation of Japanese Patent 02-248480, 10/1/1990	
EL	E17	Translation of Japanese Patent 03-090345, 4/1/1991	
EL	E18	Translation of Japanese Patent 09-278490, 10/1/1997	
EL	E19	Abstract of Japanese Patent 03-090345, 4/1/1991	
EL	E20	Abstract of Japanese Patent 09-278490, 10/1/1997	
EL	E21	BIEN ET AL., Characterization of Masking Materials for Deep Glass Micromachining, J. Micromech. Microeng. 13 pp. S34-S40 1/1/2003	
EL	E22	BRITTEN ET AL., Multiscale, Multifunction Diffractive Structures We Etched into Fused Silica for High-Laser Damage Threshold Applications, Applied Optics, Vol. 37, No. 30 10/20/1998	
EL	E23	FLETCHER ET AL., Microfabricated Silicon Solid Immersion Lens, Journal of Microelectromechanical Systems, Vol. 10, No. 3 9/1/2001	

Examiner Signature		Date Considered	8/21/06
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EL	E24	KHANDAKER ET AL., Fabrication of Microlens Arrays by Direct Electron Beam Exposure of Photoresist, Pure Appl. Opt. 6, pp. 637-641 1/1/1997	
EL	E25	KIM ET AL., Replication Qualities and Optical Properties of UV-moulded Microlens Arrays, J. Phys. D: Appl. Phys. 36; pp. 2451-2456 1/1/2003	
EL	E26	KOBAYASHI ET AL., Batch Bulk-Micromachined High-Precision Metal-On-Insulator Microspires and Their Application to Scanning Tunneling Microscopy, J. Micromech. Microeng. 14; pp. S76-S81 1/1/2004	
EL	E27	KONIJN ET AL., Nanoimprint Lithography of Sub-100nm 3D Structures, Microelectronic Engineering 78-79; pp653-658 1/1/2005	
EL	E28	KUNNAVAKKAM ET AL., Low-cost, Low-loss Microlens Arrays Fabricated by Soft-Lithography Replication Process, Applied Physics Letters, Volume 82, Number 8 2/24/2003	
EL	E29	MANSELL ET AL., Binary-Optic Smoothing with Isotropic Etching, Applied Optics; Vol. 36, No. 20 7/10/1997	
EL	E30	WAHEED ET AL., Balancing Aerial Image Intensity for Alternating Aperture Phase Shift Masks Using an Isotropic Dry-Etch, Proceedings of SPIE Vol. 5130 4/18/2003	
EL	E31	SANO ET AL., Submicron Spaced Lens Array Process Technology for a High Photosensitivity CCD Image Sensor, IEEE IEDM Dig.; pp. 283-286 1/1/1990	
EL	E32	TSUKAMOTO ET AL., High Sensitivity Pixel Technology for a 1/4 inch PAL 430k pixel IT-CCD, IEE Custom Integrated Circuits Conference 1/1/1996	

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EL	E33	YONEDA ET AL., Translation of Japanese Patent 02-248480, Transparent Substrate with Water-Repellent and Antistaining Properties, and Structure Equipped Therewith 10/4/1990	
EL	E34	YONEDA ET AL., Translation of Japanese Patent 02-248480, Transparent Substrate Material with Water-Replent and Anti-Staining Properties and Structure Equipped with Same 10/4/1990	

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